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U	S. DEPARTMENT OF	COMMERCE	
P/	ATENT AND TRADEM.	ARK OFFICE	
INFORMATION DISCLO	SURE	Docket Number	
STATEMENT		10191/3746	
Application Number	Filing Date	Examiner	Art Unit
To BLUS 25537033	Herewith	To Be Assigned	To Be Assigned
Invention Title		Inventor(s)	
RECONSTRUCTION OF AN		HAKVOORT et a	
FROM THE SENSOR SIGN	AL OF A ROTATION		
ANGLE SENSOR			

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

- In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and in conformance with the procedures of 37 C.F.R. §§ 1.97 and 1.98 and M.P.E.P. § 609, attorneys for Applicants hereby bring the following reference to the attention of the Examiner. The reference is listed on the attached modified PTO form 1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference be made of record therein and appear among the "References Cited" on any patent to issue therefrom.
- A copy of each patent, publication or other information listed on the modified PTO form 1449 is enclosed, except as otherwise indicated on the modified PTO form 1449.

Dated: 5/31/05

By: 122 aget (8. Nr. 41,172)

By: 14 72 g

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JC20 Rec'd PCT/PTO 31 MAY 2005

	Atty. Docket No. 10191/3746		10 x 5 3 7 0	33
INFORMATION DISCLOSURE STATEMENT BY APPLICANTS PTO FORM 1449	Applicant(s) HAKVOORT	et al.		
	Filing Date 1 Herewith	11/14/2005	Group To De Assigned	2856

U. S. PATENT DOCUMENTS

	EXAMINER'S INITIALS	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE
1							

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSL	ATION
						YÉS	NO
-	11 037 800*	May 31, 1999	Japan				

Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority).

OTHER DOCUMENTS

EXAMINER'S INITIALS	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.

EXAMINER /Paul West/ (02/25/2008)

DATE CONSIDERED 02/25/2008

EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Insider with the M.P.E.P. 609; draw line through citation if not in conformance and not considered. Insider with the M.P.E.P. 609; draw line through citation if not in conformance and not considered. Insider with the M.P.E.P. 609; draw line through citation if not in conformance and not considered. Insider with the M.P.E.P. 609; draw line through citation if not in conformance and not considered. Insider with the M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation if not in conformance with M.P.E.P. 609; draw line through citation is not in conformance with M.P.E.P. 609; draw line through citation is not include the conformance with M.P.E.P. 609; draw line through citation is not include the citation in conformance with M.P.